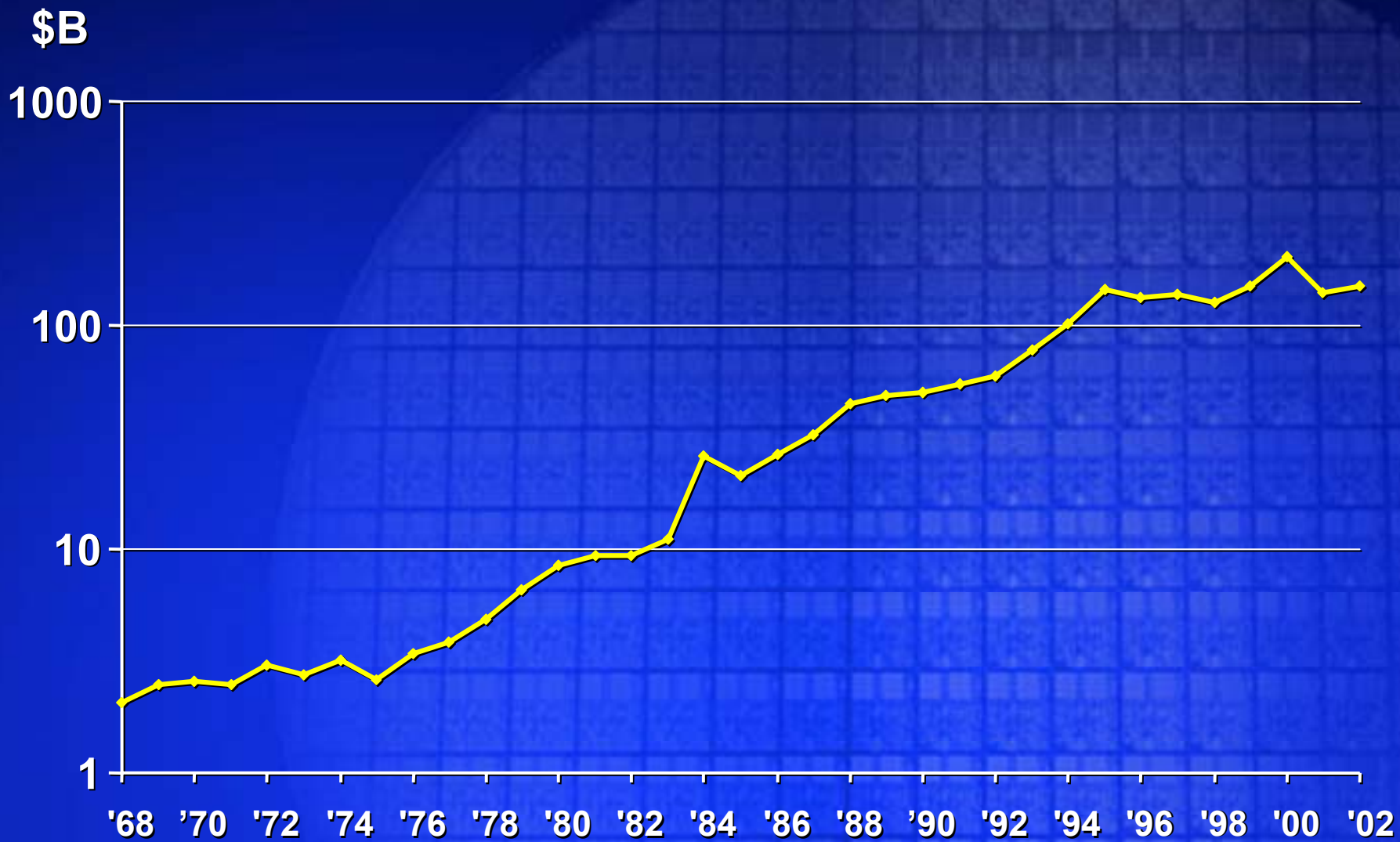


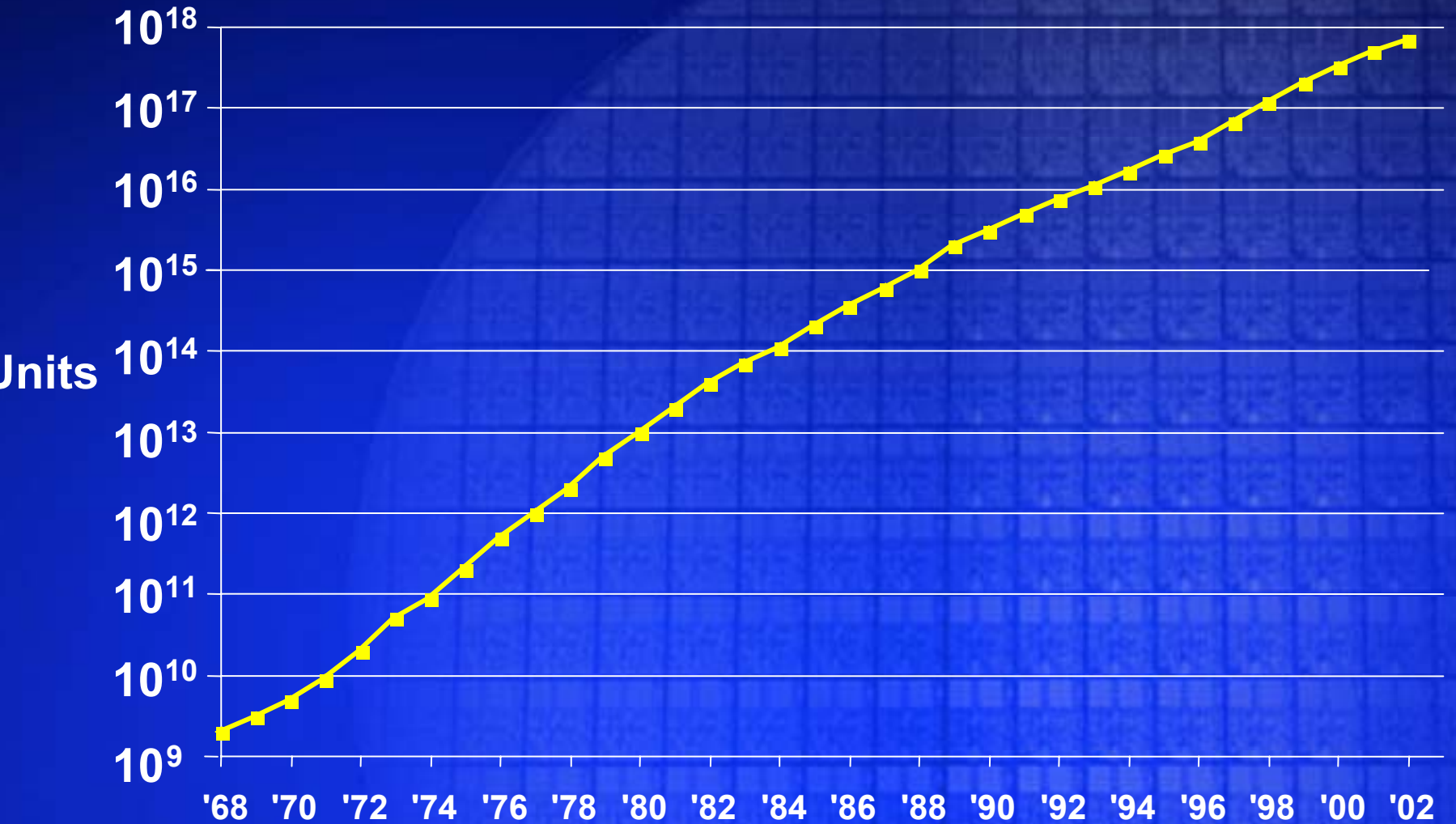
**NO EXPONENTIAL IS FOREVER ...**

**Gordon E. Moore**

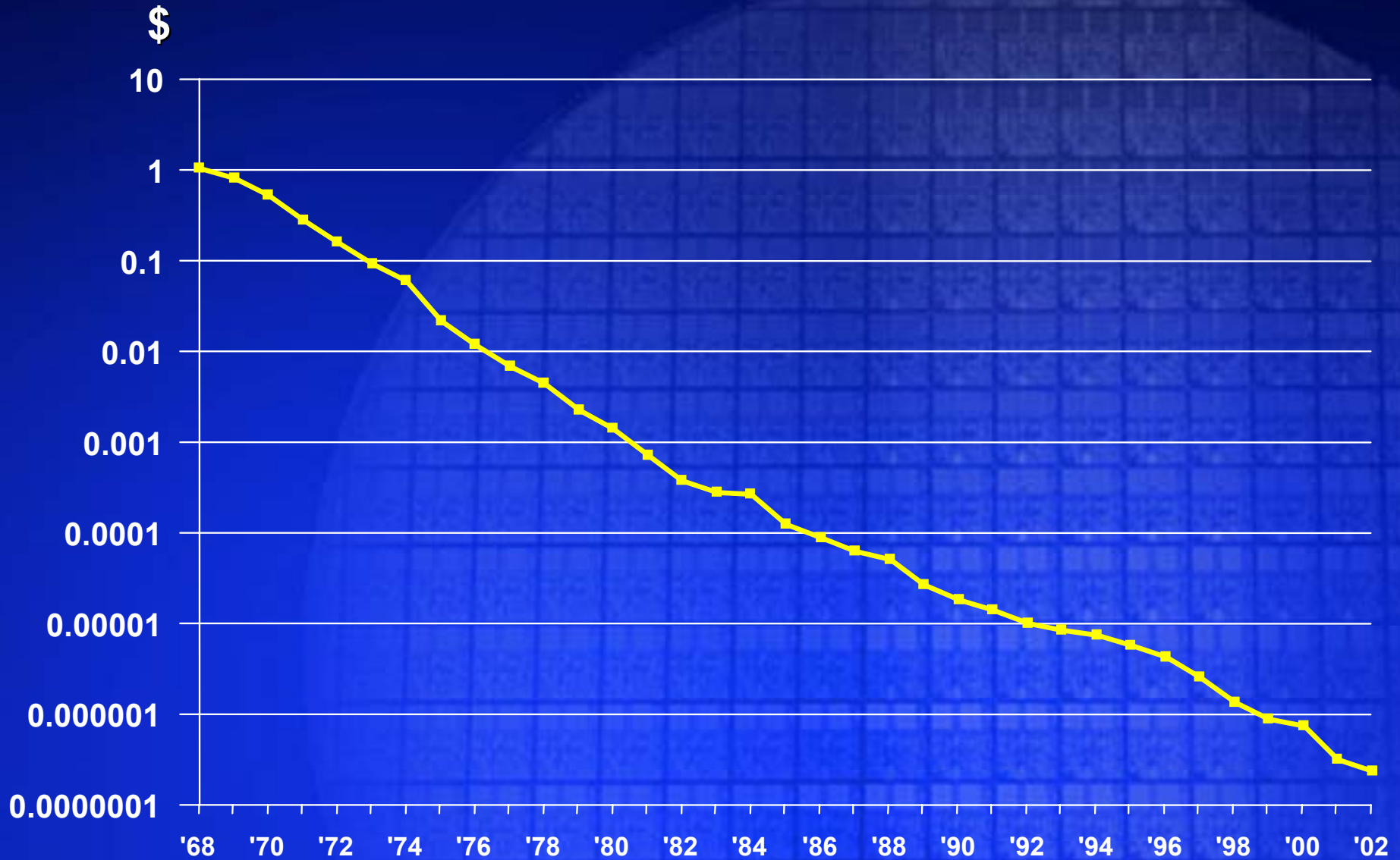
# Worldwide Semiconductor Revenues



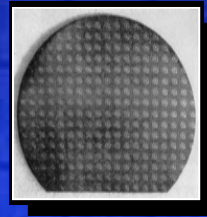
# Transistors Shipped Per Year



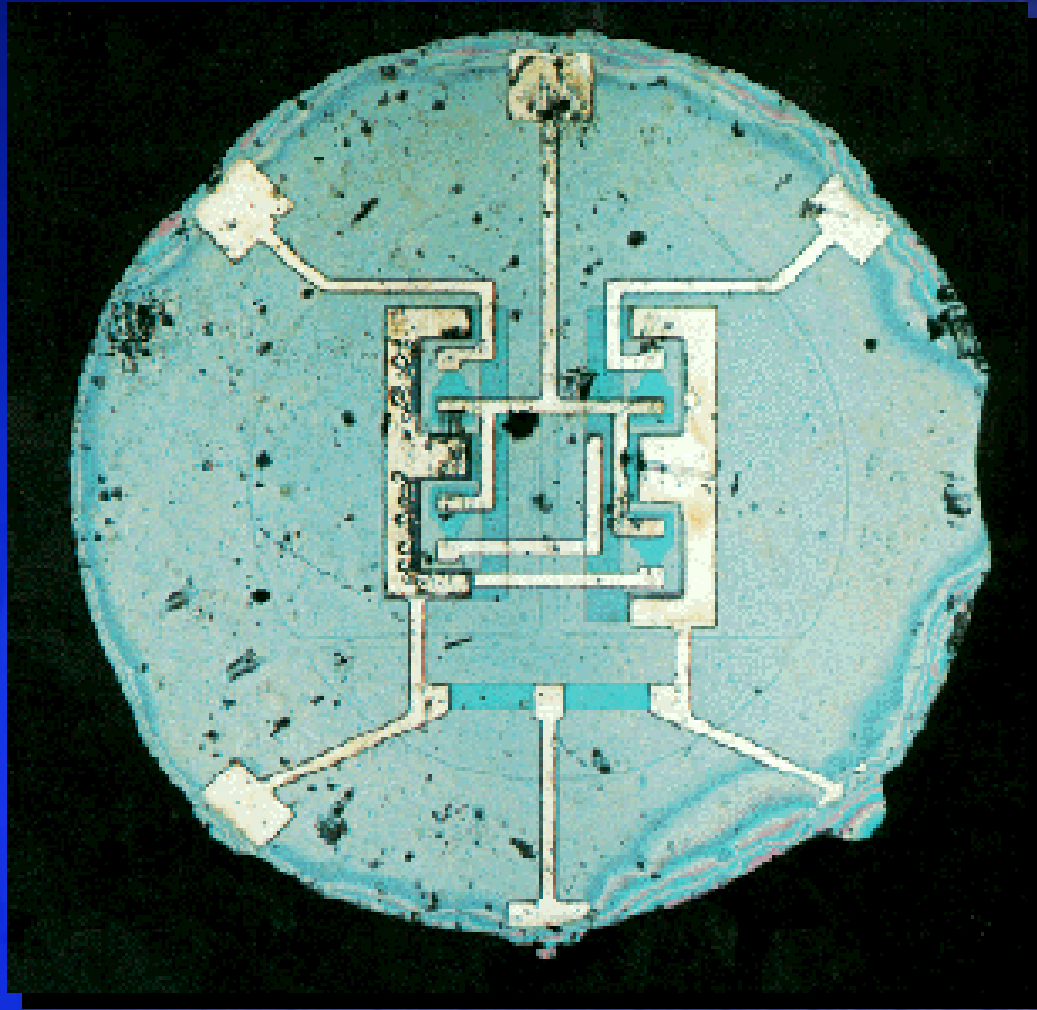
# Average Transistor Price By Year



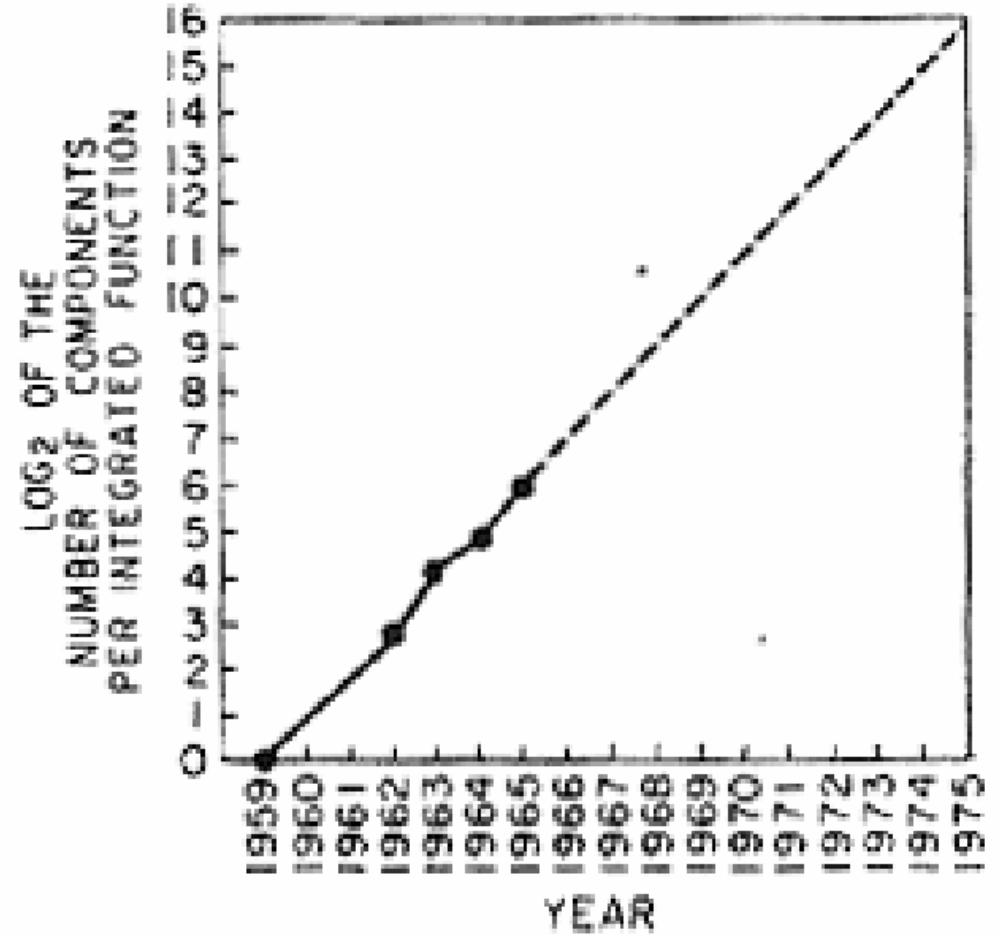
# 1" Wafer Of Planar Transistors, ~1959



# The First Planar Integrated Circuit, 1961



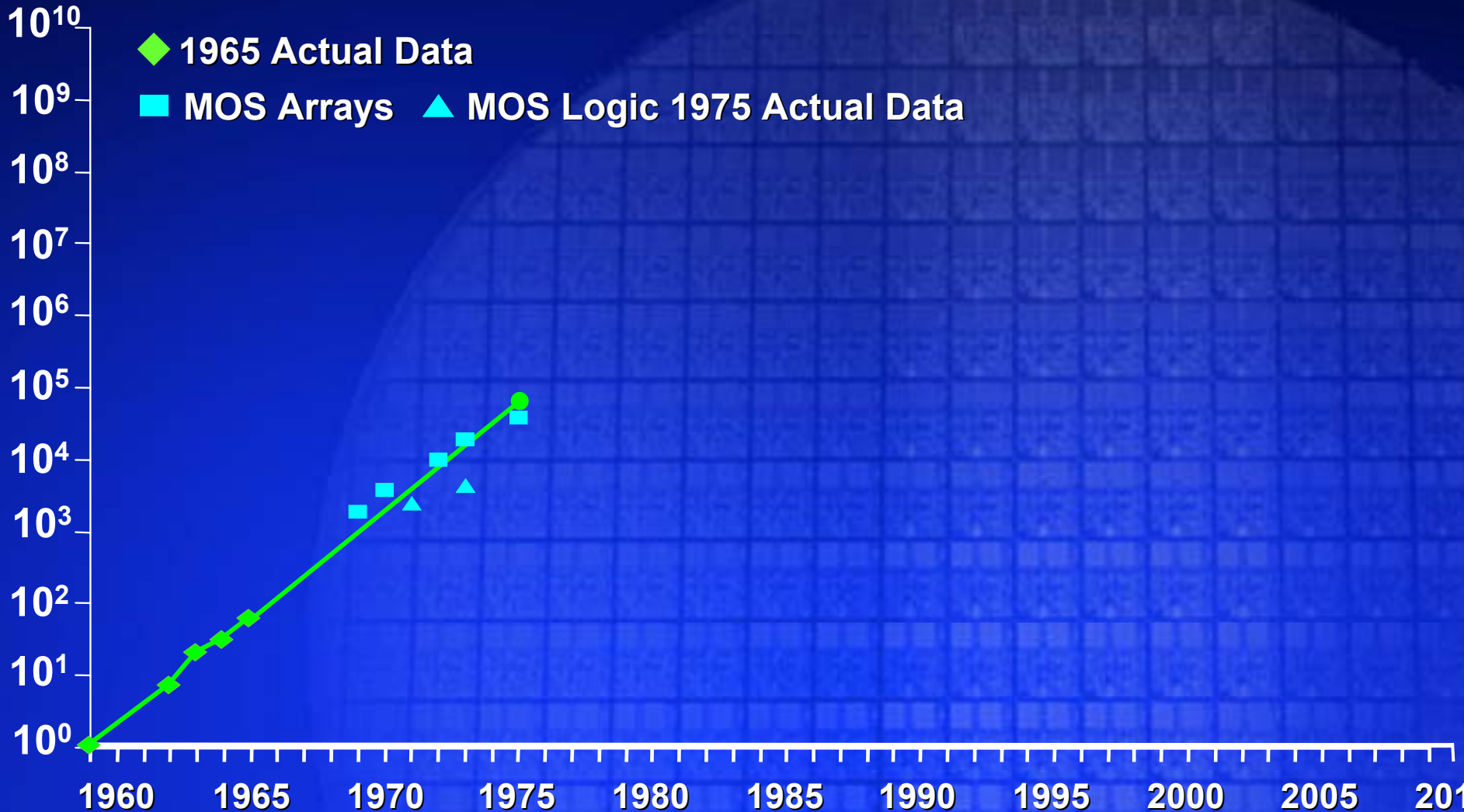
# 1965 Transistor Projection



# Integrated Circuit Complexity

Transistors  
Per Die

◆ 1965 Actual Data  
■ MOS Arrays ▲ MOS Logic 1975 Actual Data

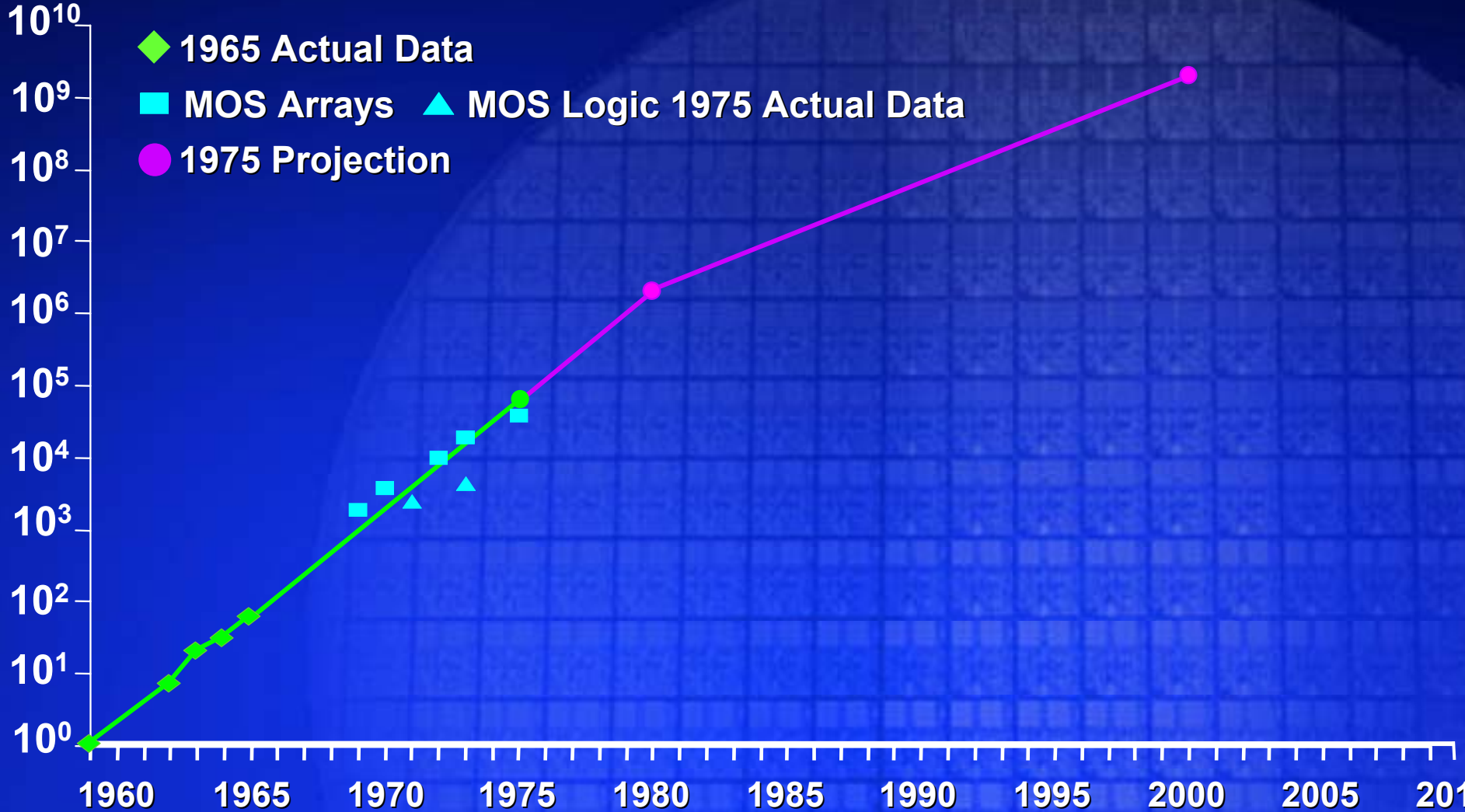




# Integrated Circuit Complexity

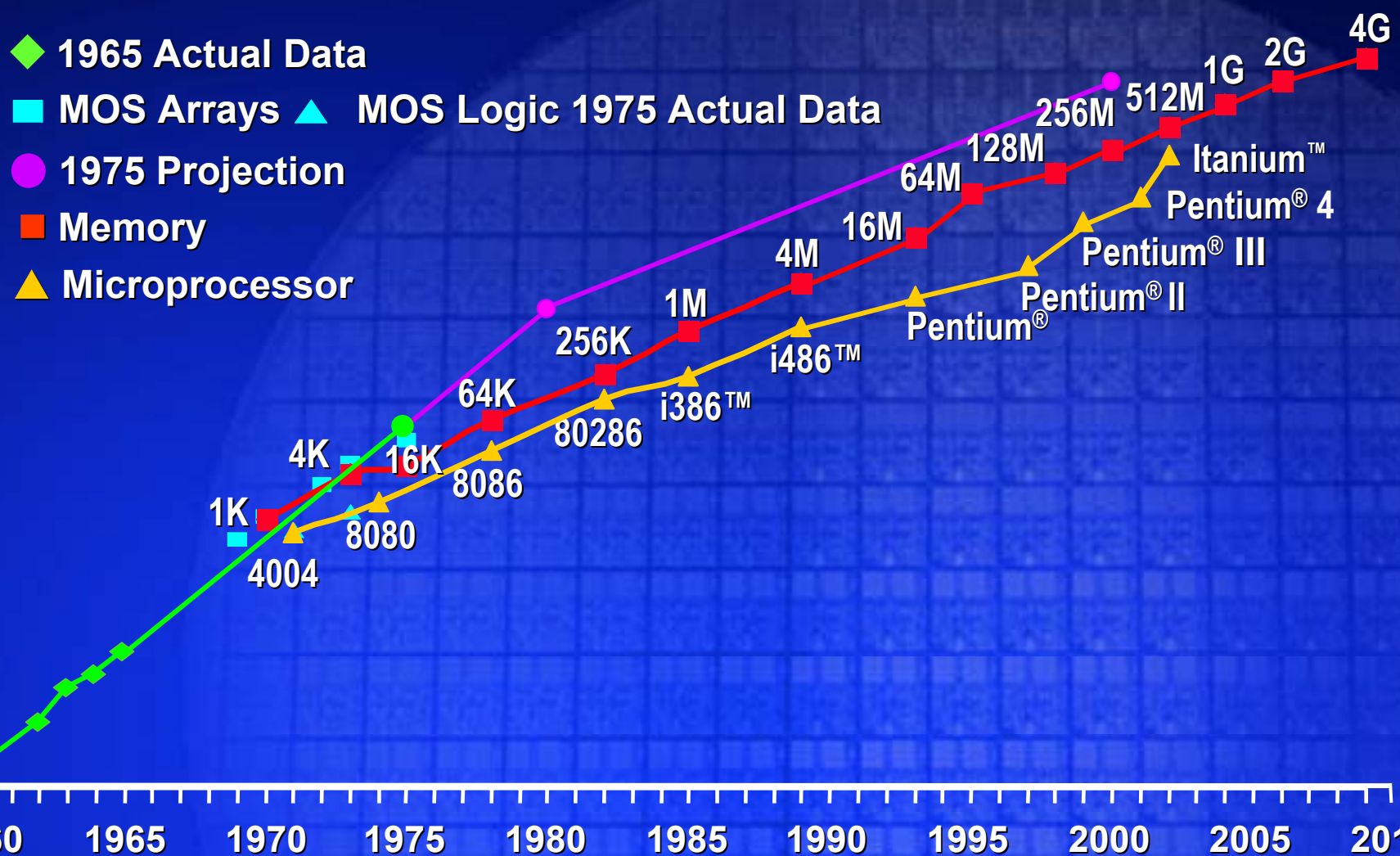
Transistors  
Per Die

- ◆ 1965 Actual Data
- MOS Arrays ▲ MOS Logic 1975 Actual Data
- 1975 Projection

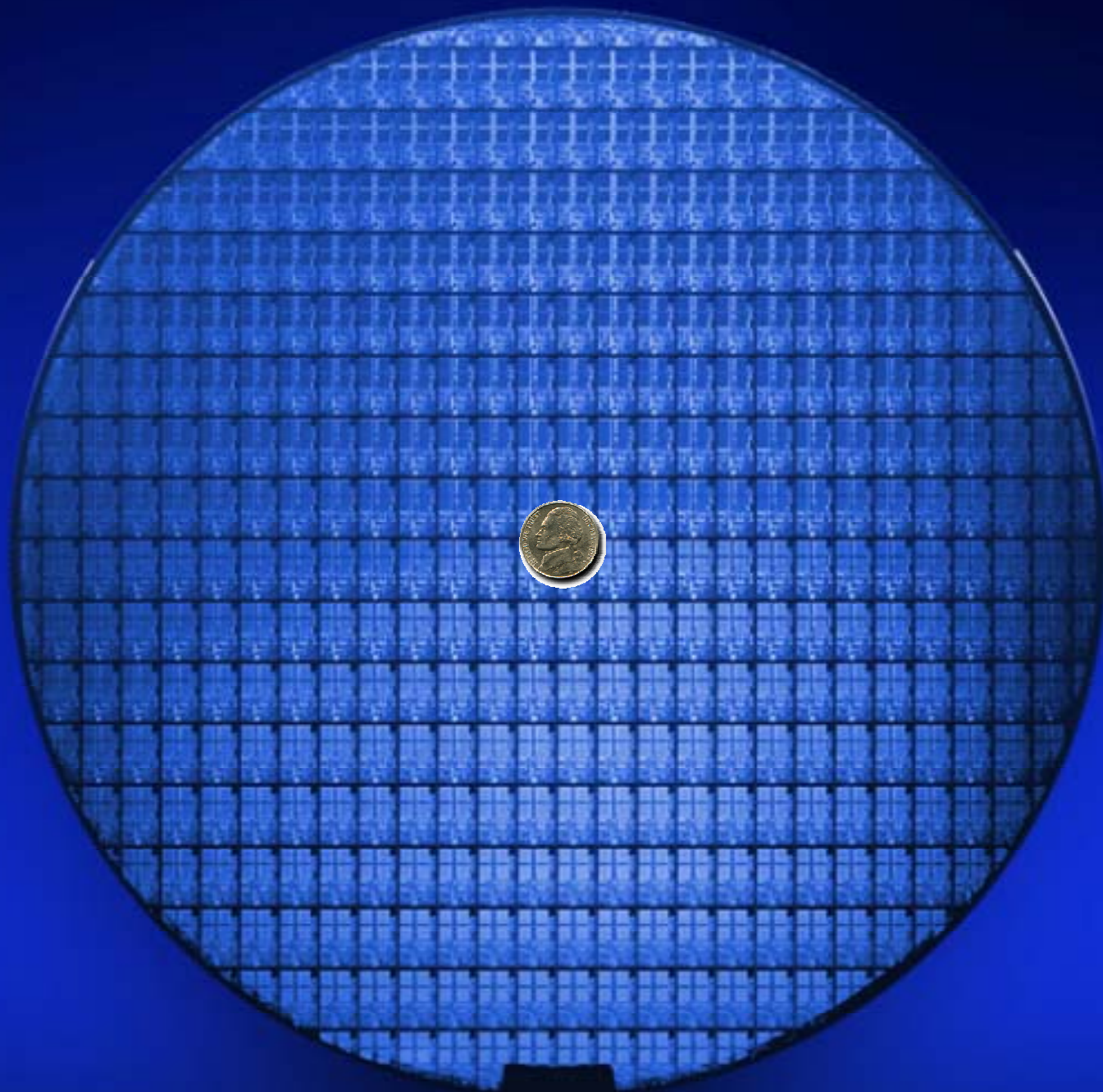


# Integrated Circuit Complexity

Transistors  
Per Die



# 300mm Wafer

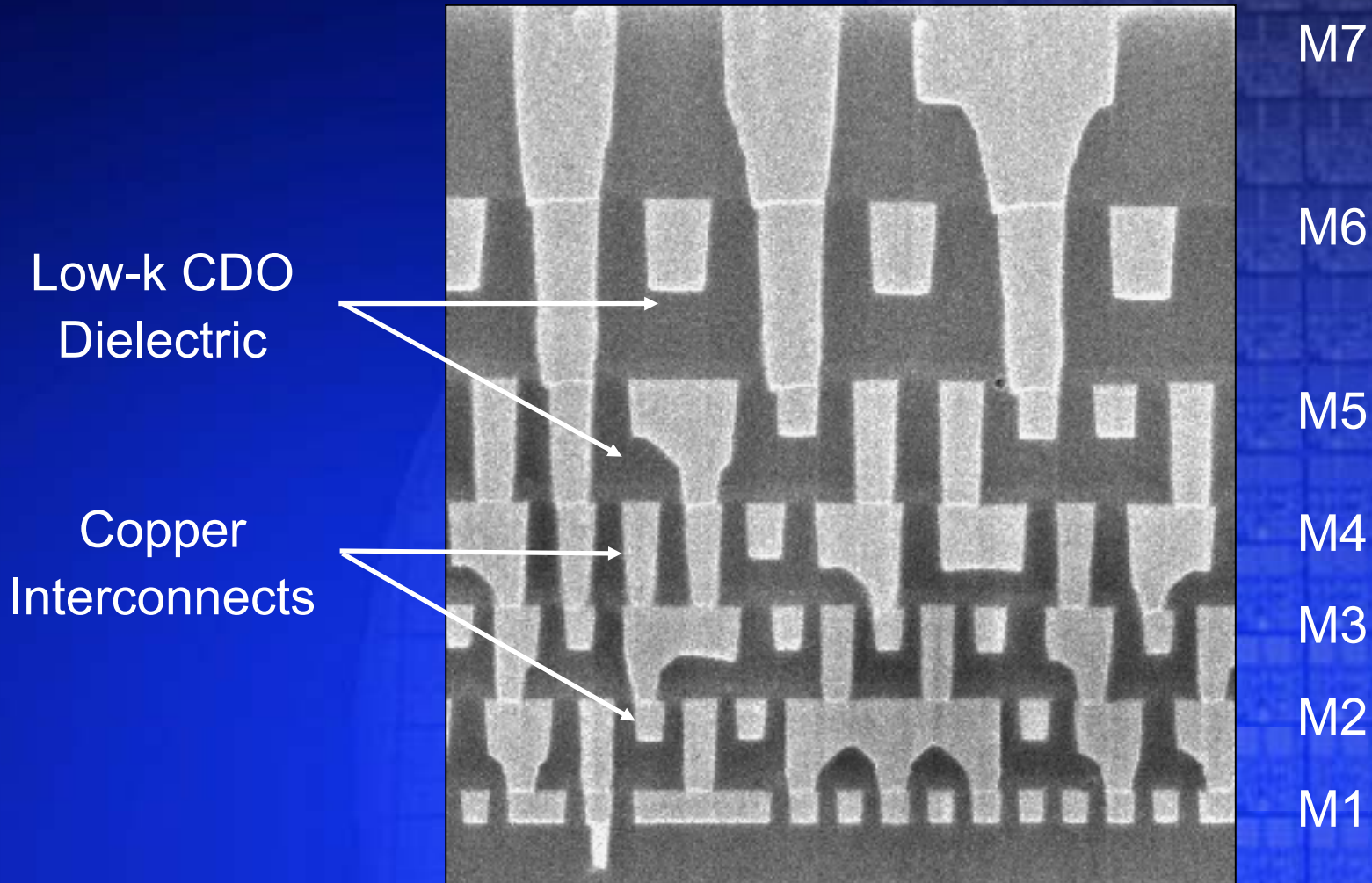


# Projected 2000 Wafer, circa 1975



**Moore was not always accurate**

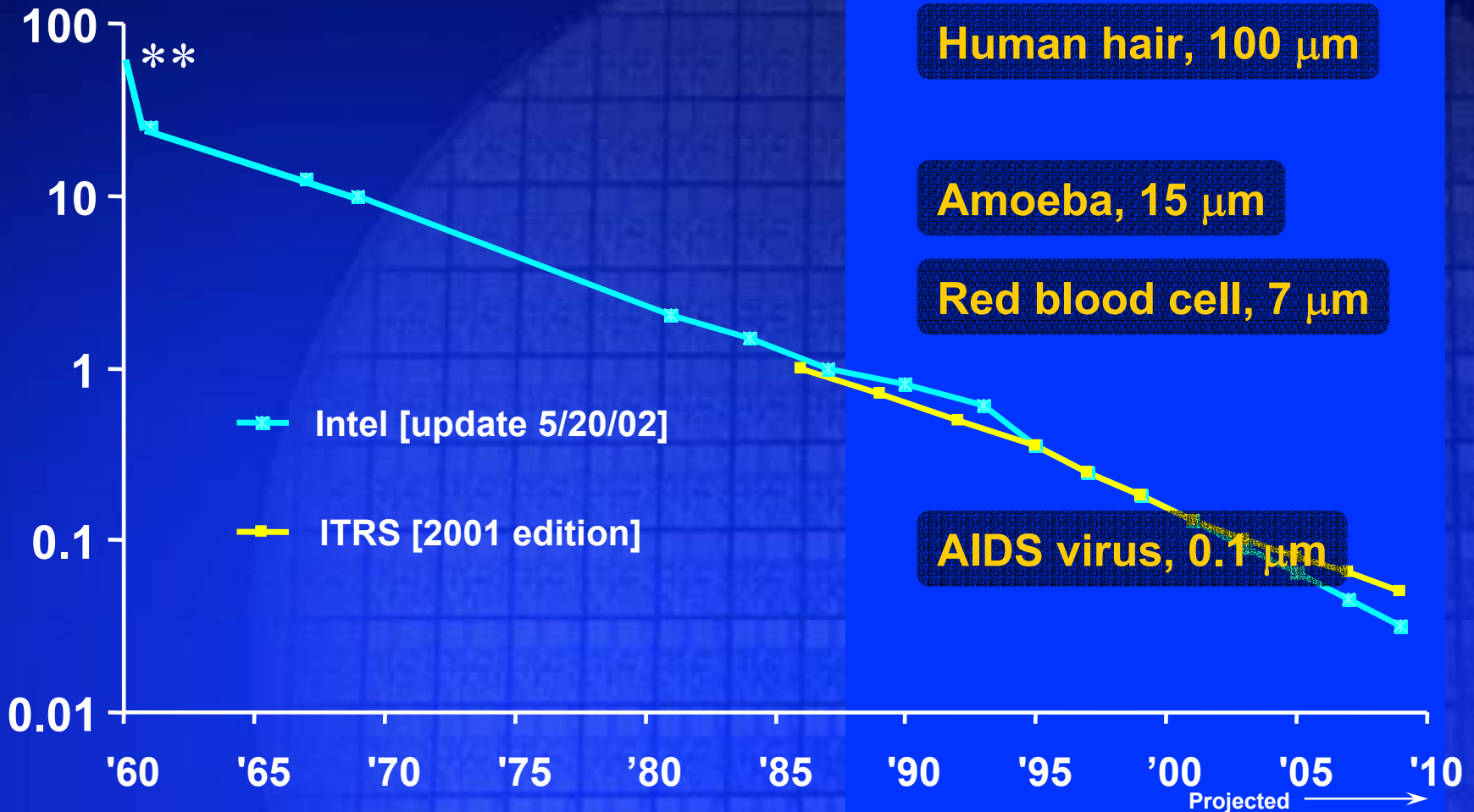
# 90 nm Generation Interconnects



Combination of copper + low-k dielectric now meeting performance and manufacturing goals

# Minimum Feature Size

Feature Size  
(microns)



\*\* Planar Transistor; remaining data points are ICs.  
Source: Intel, post '96 trend data provided by SIA  
International Technology Roadmap for Semiconductors (ITRS)

# 1 $\mu\text{m}^2$ SRAM Cell

P501 Contact  
1978

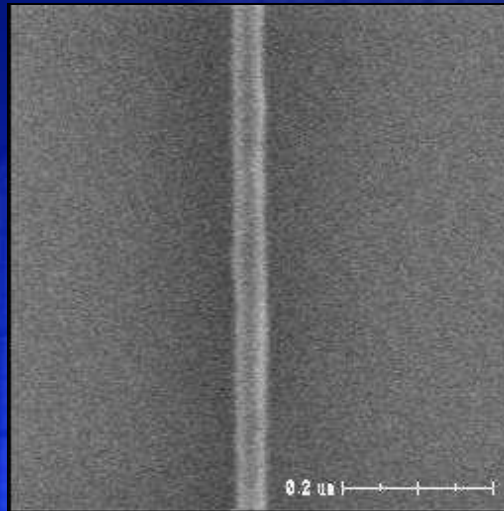
P1262 SRAM Cell  
2002



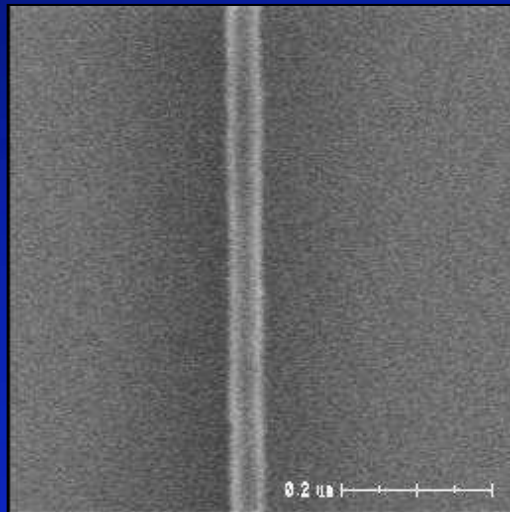
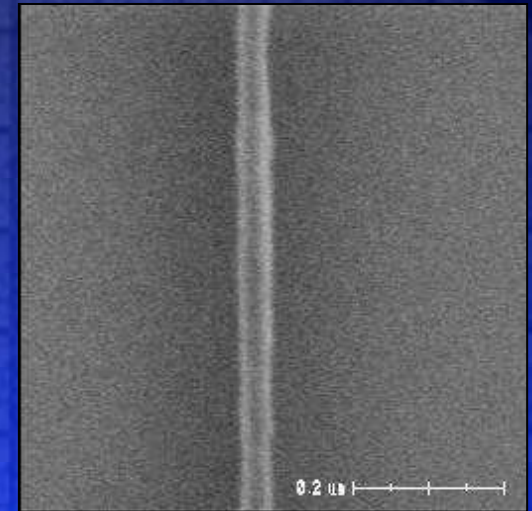
1  $\mu\text{m}$

# 50nm Resist Lines With 193nm Light

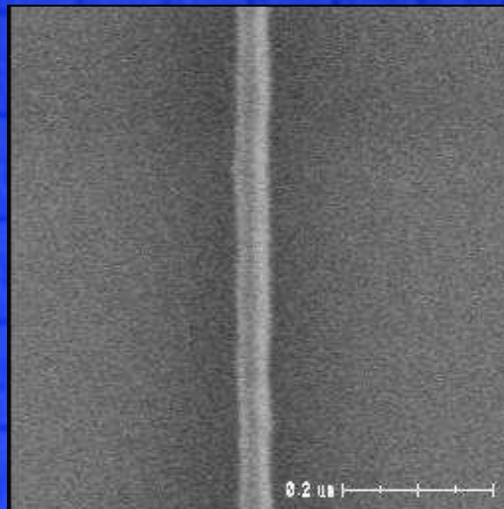
-0.2um focus



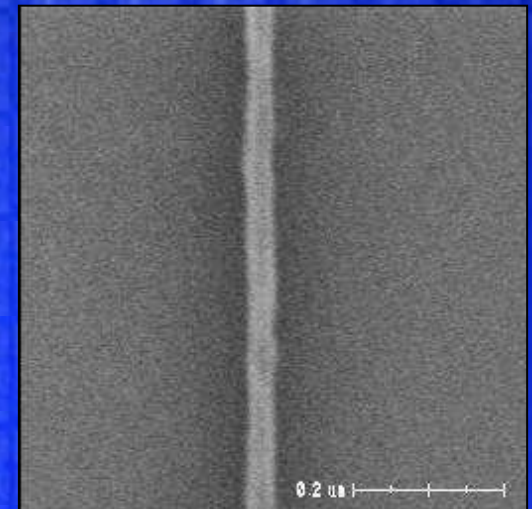
-0.3um focus



“best focus”



+0.2um focus



+0.3um focus

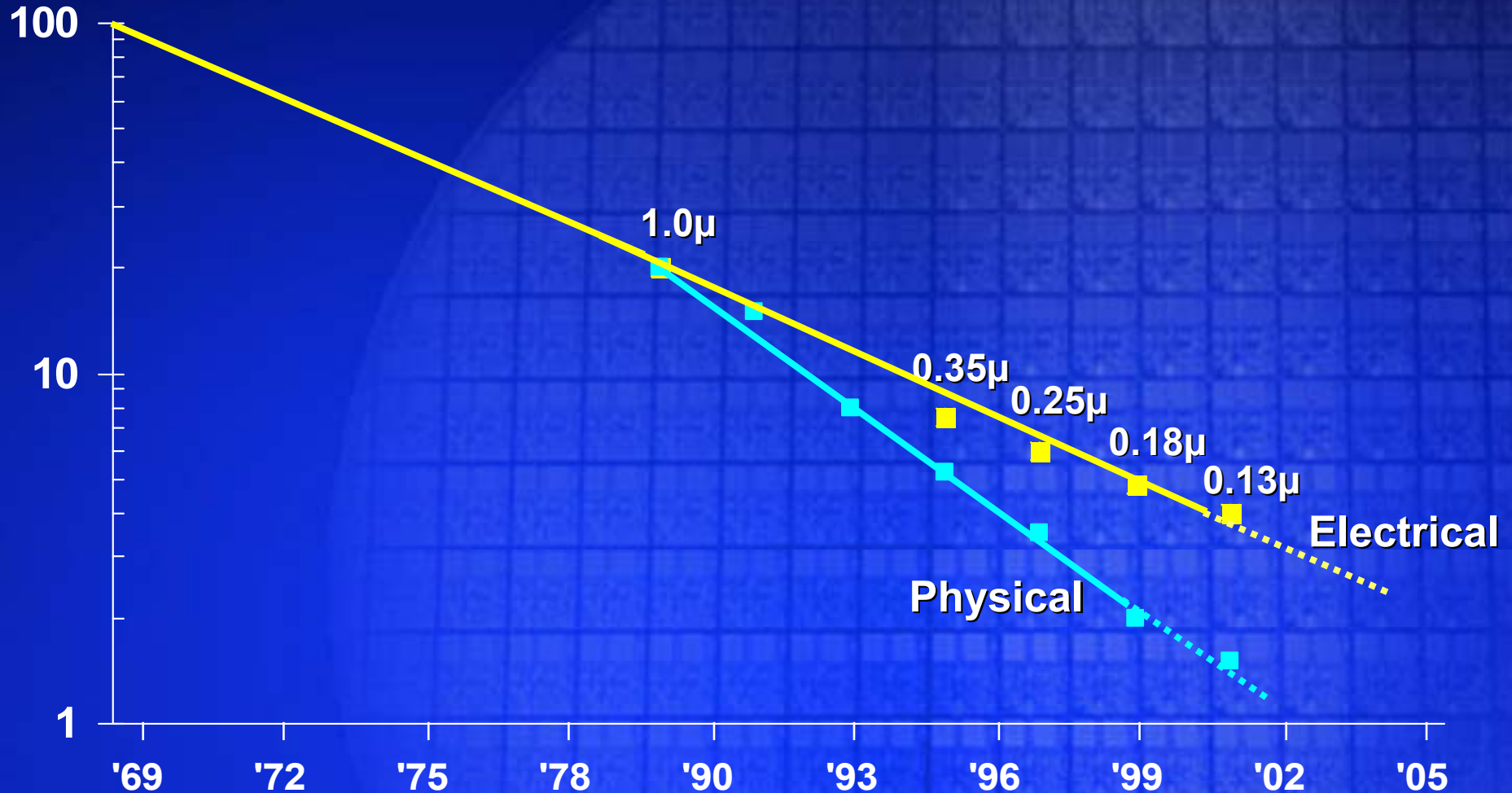


# 193nm Step and Scan Production Tool

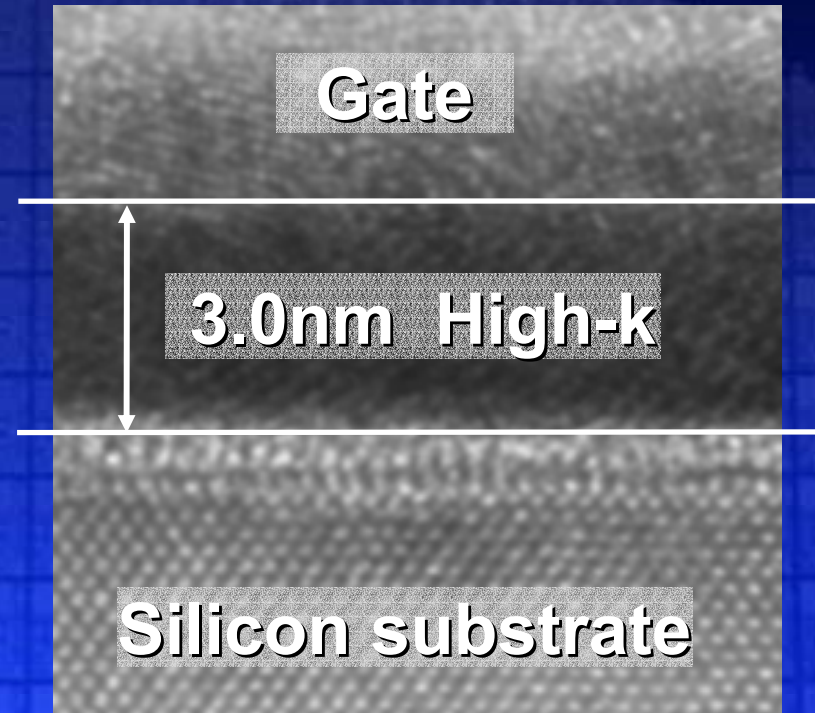
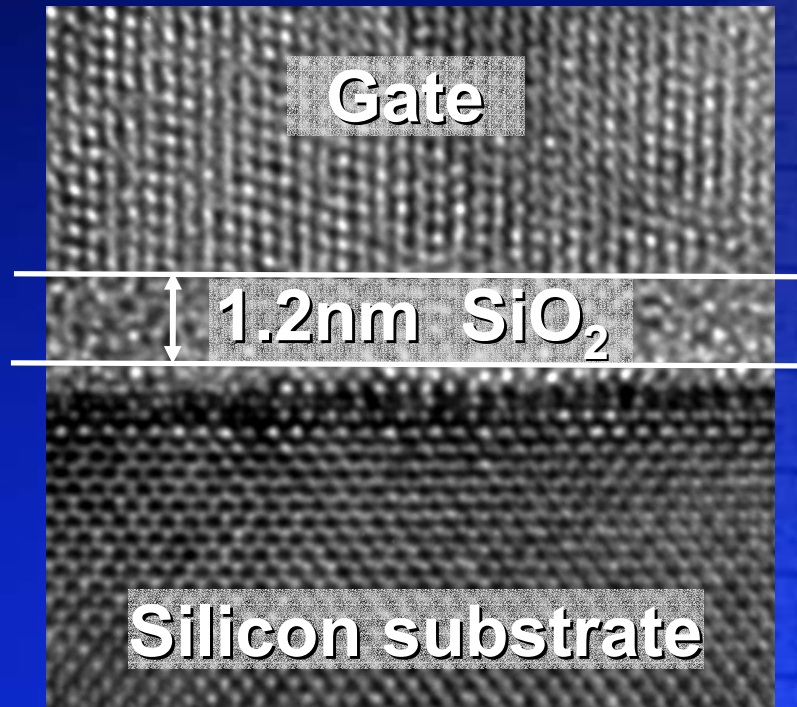


# Minimum Insulator Thickness vs Time

Oxide Thickness  
(Nanometers)



# High K for Gate Dielectrics

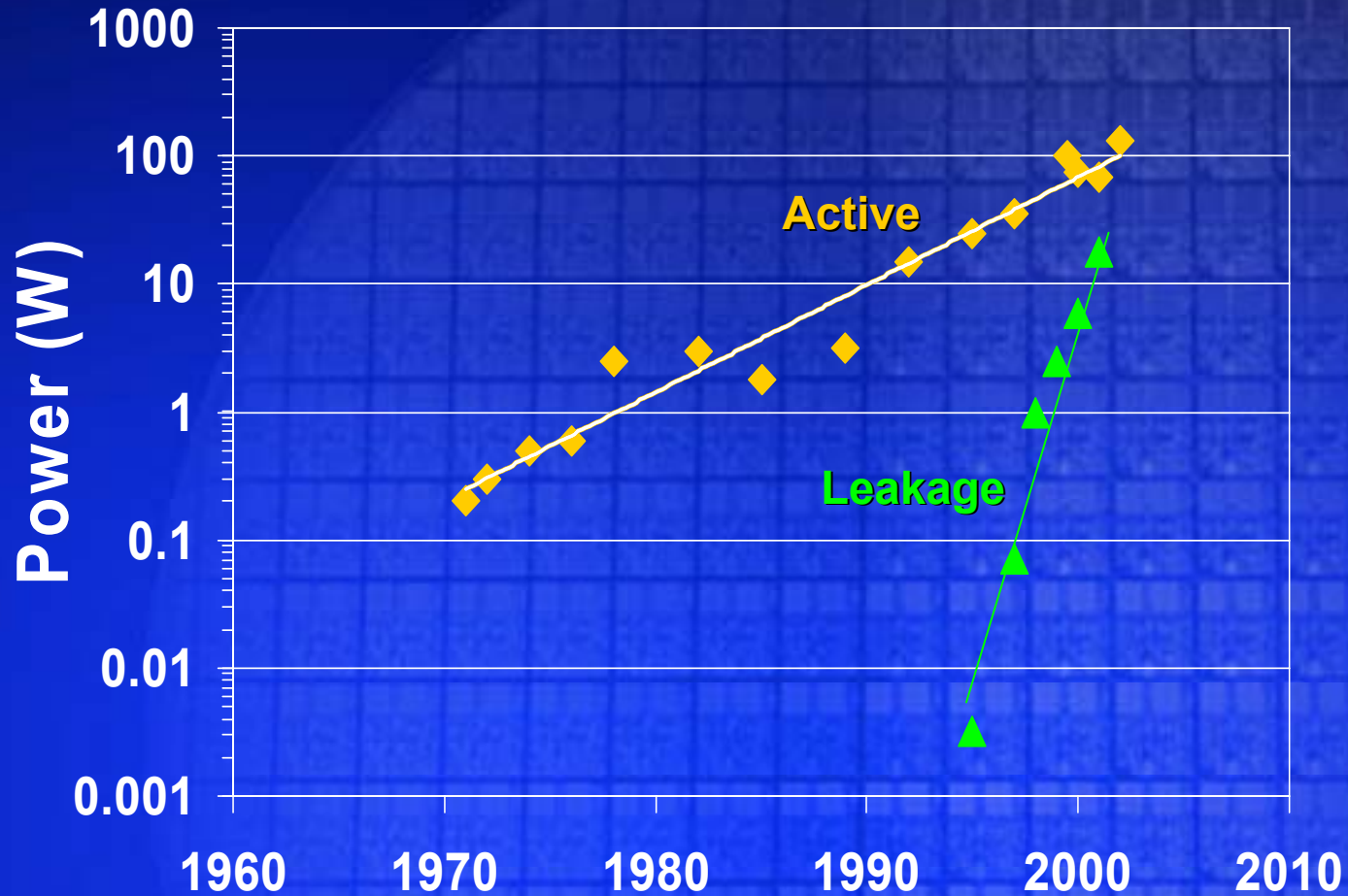


	90nm process	Experimental high-k
Capacitance	1X	1.6X
Leakage	1X	< 0.01X

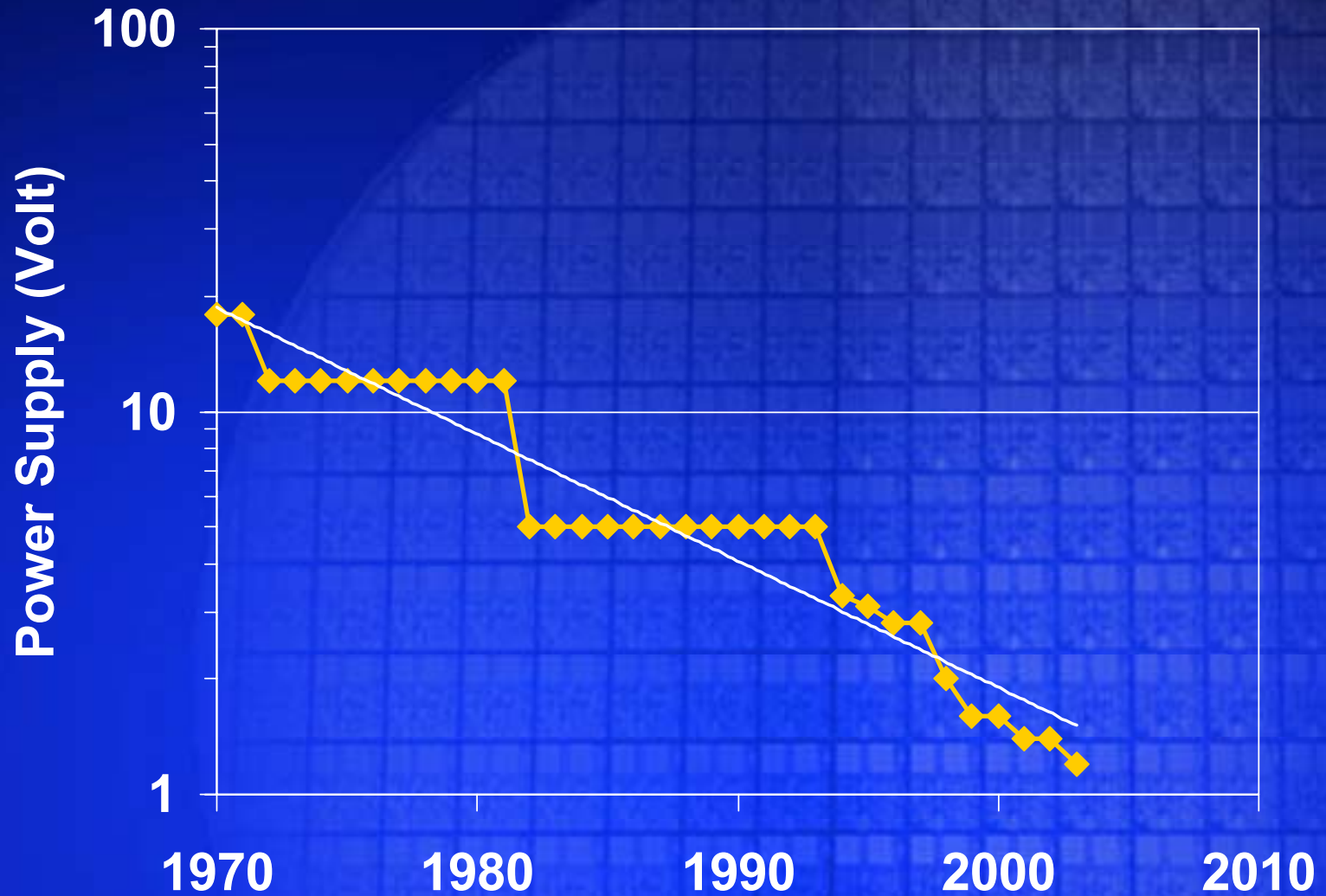
# Processor Performance (MIPS)



# Processor Power (Watts) - Active & Leakage



# Processor Supply Voltage

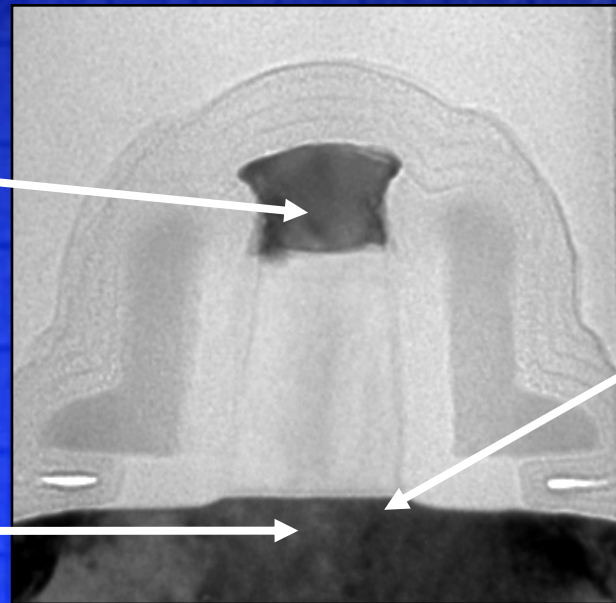


# New Materials and Device Structures Extending Transistor Scaling

*Changes  
Made*

Gate  
Silicide  
Added

Channel  
Strained  
Silicon



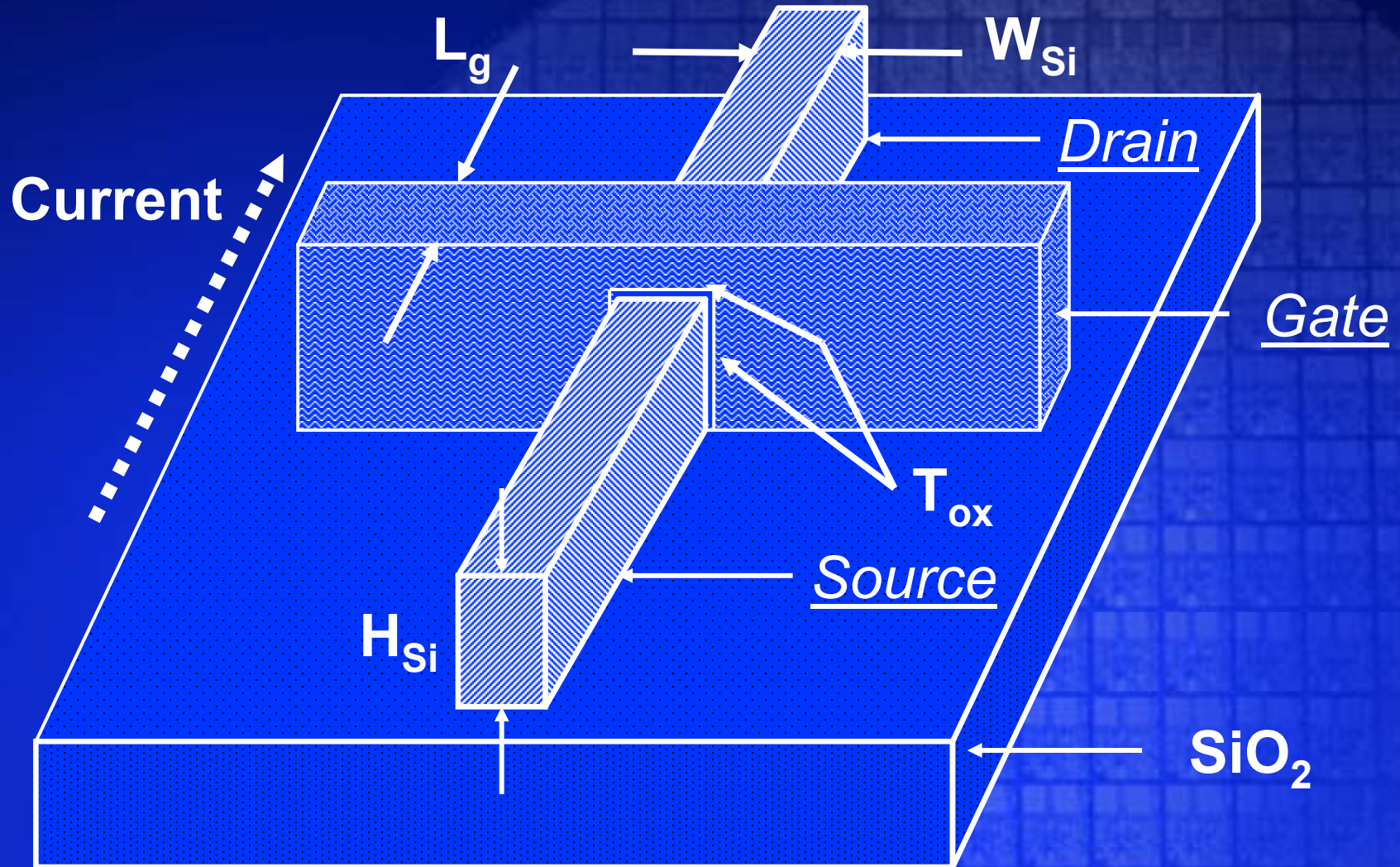
*Future  
Options*

High-k  
Gate  
Dielectric

New  
Transistor  
Structure

**Transistor**

# Tri-Gate Transistor Structure





# Technology Generations to Come

Double the Density  
Reduce Line Width by 0.7x

**130nm → 90nm → 60nm → 45nm → 30nm → ?**

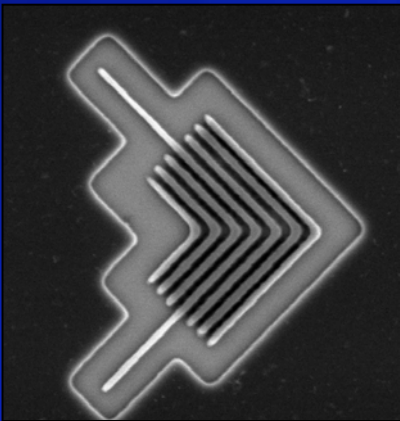
2 or 3 years between generations

∴

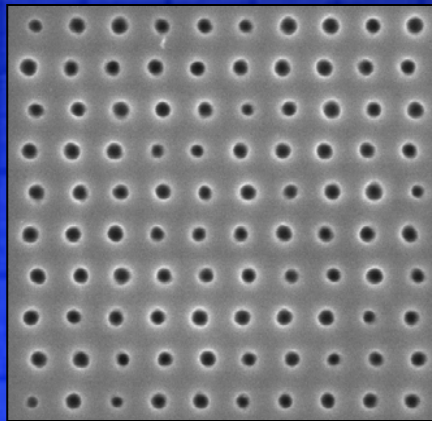
~10 ± 2 Years

# EUV Printed and Etched Lines

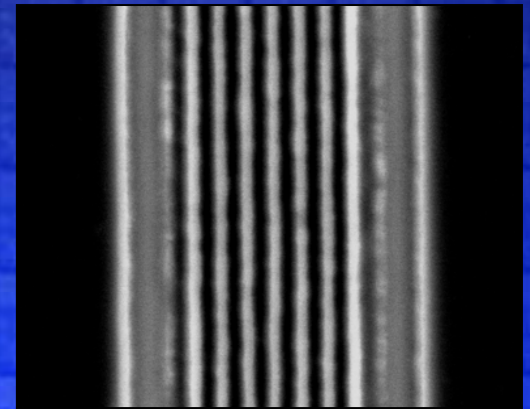
100 nm,  $k_1 = 0.75$



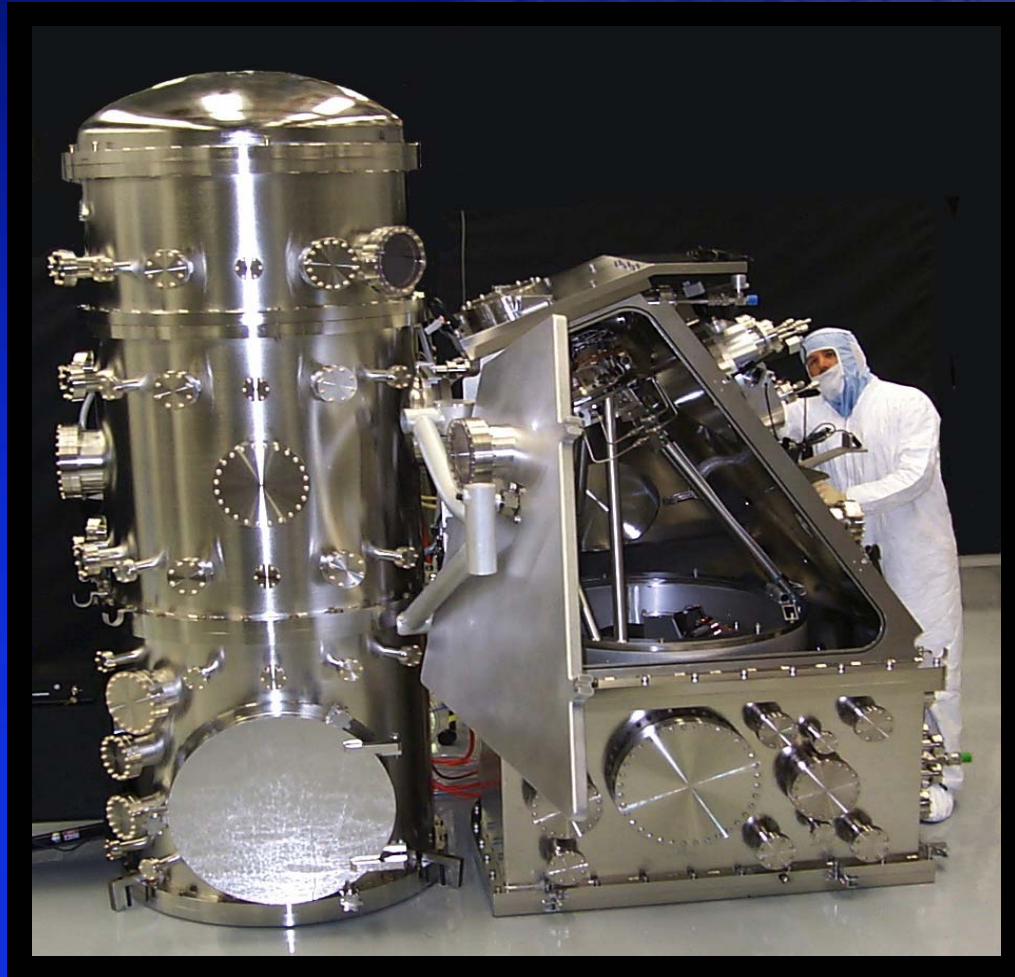
80 nm,  $k_1 = 0.60$



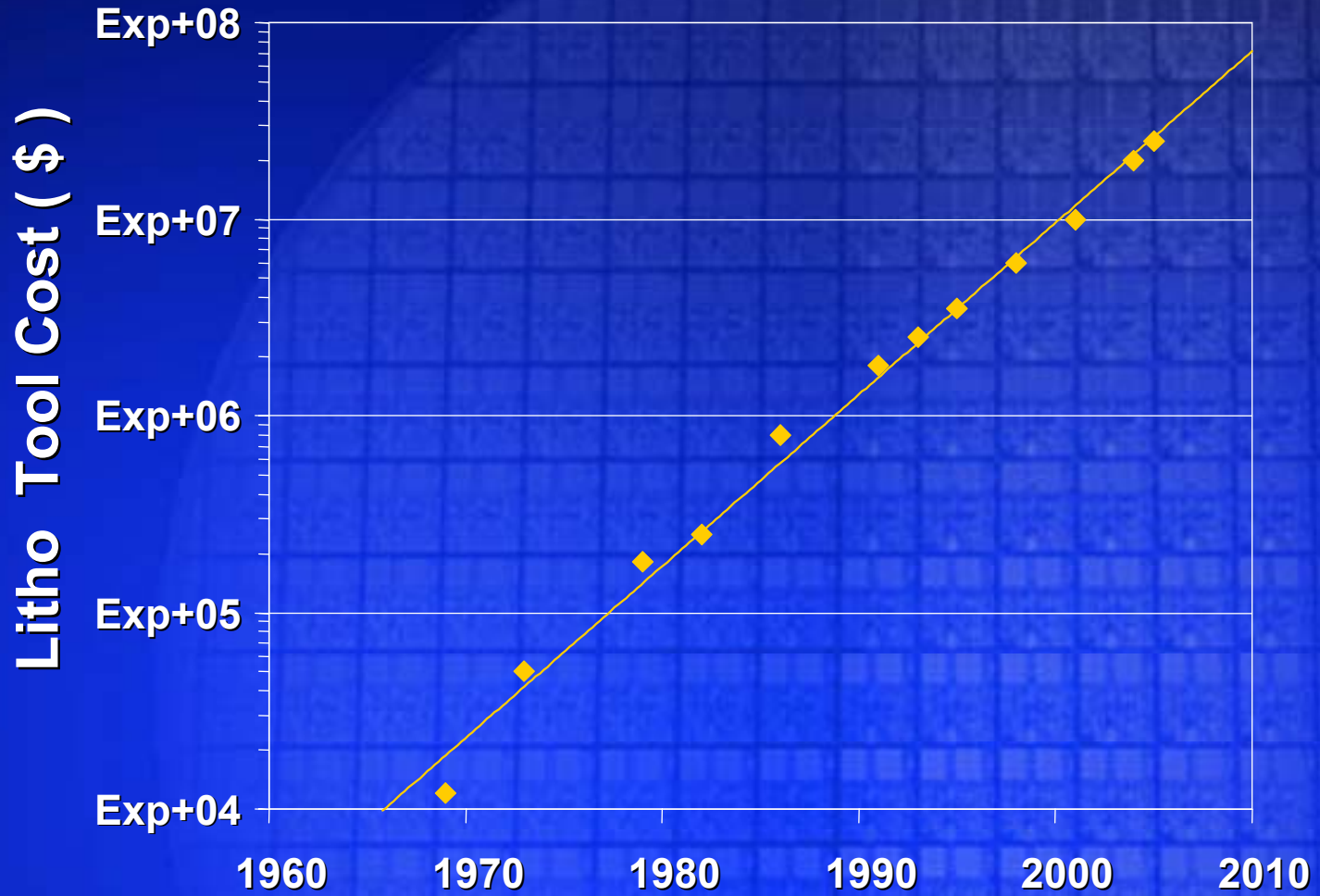
50 nm dense,  $k_1 = 0.37$



# Extreme Ultraviolet (EUV) Lithography



# Lithography Tool Cost ( \$ )



**NO EXPONENTIAL IS FOREVER ...**

**BUT**

**WE CAN DELAY “FOREVER”**